

Xiaoyang Zhang

List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/10529505/publications.pdf>

Version: 2024-02-01

24
papers

298
citations

1040056

9
h-index

1199594

12
g-index

24
all docs

24
docs citations

24
times ranked

268
citing authors

#	ARTICLE	IF	CITATIONS
1	An Electrothermal Cu/W Bimorph Tip-Tilt-Piston MEMS Mirror with High Reliability. <i>Micromachines</i> , 2019, 10, 323.	2.9	22
2	Ultralow-voltage electrothermal MEMS based fiber-optic scanning probe for forward-viewing endoscopic OCT. <i>Optics Letters</i> , 2019, 44, 2232.	3.3	12
3	A fiber scanner based on a robust Cu/W bimorph electrothermal MEMS stage. , 2019, , .		1
4	A Miniature Lens Scanner with an Electrothermally-Actuated Micro-Stage. , 2018, , .		1
5	Thermal Reliability Study of an Electrothermal MEMS Mirror. <i>IEEE Transactions on Device and Materials Reliability</i> , 2018, 18, 422-428.	2.0	8
6	Integrated Optoelectronic Position Sensor for Scanning Micromirrors. <i>Sensors</i> , 2018, 18, 982.	3.8	7
7	An ultra-fast electrothermal micromirror with bimorph actuators made of copper/tungsten. , 2017, , .		6
8	Characterization and reliability study of a MEMS mirror based on electrothermal bimorph actuation. , 2017, , .		2
9	Miniature Fourier transform spectrometer with a dual closed-loop controlled electrothermal micromirror. <i>Optics Express</i> , 2016, 24, 22650.	3.4	13
10	A large range micro-XZ-stage with monolithic integration of electrothermal bimorph actuators and electrostatic comb drives. , 2016, , .		4
11	A wide-angle immersed MEMS mirror and its application in optical coherence tomography. , 2016, , .		4
12	VO ₂ -Based MEMS Mirrors. <i>Journal of Microelectromechanical Systems</i> , 2016, 25, 780-787.	2.5	28
13	A Self-Aligned 45°-Tilted Two-Axis Scanning Micromirror for Side-View Imaging. <i>Journal of Microelectromechanical Systems</i> , 2016, 25, 799-811.	2.5	6
14	Wide-angle structured light with a scanning MEMS mirror in liquid. <i>Optics Express</i> , 2016, 24, 3479.	3.4	37
15	A Fast, Large-Stroke Electrothermal MEMS Mirror Based on Cu/W Bimorph. <i>Micromachines</i> , 2015, 6, 1876-1889.	2.9	36
16	Model-Based Angular Scan Error Correction of an Electrothermally-Actuated MEMS Mirror. <i>Sensors</i> , 2015, 15, 30991-31004.	3.8	9
17	A non-resonant fiber scanner based on an electrothermally-actuated MEMS stage. <i>Sensors and Actuators A: Physical</i> , 2015, 233, 239-245.	4.1	19
18	A 45°-tilted 2-axis scanning micromirror integrated on a silicon optical bench for 3D endoscopic optical imaging. , 2015, , .		5

#	ARTICLE	IF	CITATIONS
19	A robust, fast electrothermal micromirror with symmetric bimorph actuators made of copper/tungsten. , 2015, , .		8
20	An endoscopic forward-viewing OCT imaging probe based on a two-axis scanning mems mirror. , 2014, , .		5
21	MEMS-based 3D confocal scanning microendoscope using MEMS scanners for both lateral and axial scan. Sensors and Actuators A: Physical, 2014, 215, 89-95.	4.1	55
22	Confocal microendoscopic 3D imaging using MEMS scanners for both lateral and axial scans. , 2013, , .		1
23	An electrothermal/electrostatic dual driven MEMS scanner with large in-plane and out-of-plane displacement. , 2013, , .		3
24	Repeatability study of 2D MEMS mirrors based on S-shaped Al/SiO ₂ bimorphs. , 2013, , .		6